

# PRODUCT/PROCESS CHANGE NOTICE (PCN)

Product Affected	IDT74ALVCHS162830, IDTCSP2510	MEANS OF DISTINGUISHING CHANGED DEVICES:  ☐ Product Mark ☐ Back Mark ☐ Date Code Top mark will have "4" following the ☐ Other die revision.
Date Effective:	June 15, 2002	Unter the revision.
Contact:	Bimla Paul	_
Title:	Quality Assurance Manager	Attachment:: Yes No
Phone #:	(408)-654-6419	
Fax #:	(408)-492-8362	Samples: Available upon request.
E-mail:	bimla.paul@idt.com	
	AND PURPOSE OF CHANGE:	
<ul> <li>□ Die Technolog</li> <li>□ Wafer Fabrica</li> <li>□ Assembly Pro</li> <li>□ Equipment</li> <li>□ Material</li> <li>□ Testing</li> <li>■ Manufacturing</li> <li>□ Data Sheet</li> <li>□ Other</li> </ul>	ttion Process Hillsboro, Oregon (F cess IDT's wafer fab facil	r fab production from Salinas, California (Fab 2) to tab 4), these qualified Logic products will be transferred to ity in Hillsboro, Oregon. There is no change in die technology.
	QUALIFICATION SUMMARY: ng will verify that there is no change to the prod	uct reliability. Please see attachment for qualification
IDT records indi to grant approva it will be assume IDT reserves the	l or request additional information. If IDT does not that this change is acceptable.	change. Please use the acknowledgement below or E-Mail not receive acknowledgement within 30 days of this notice the process change effective date until the inventory
Customer:		Approval for shipments prior to effective date.
Name/Date:	E-	Mail Address:
Title:	Pl	none# /Fax# :
CUSTOMER C	OMMENTS:	
IDT ACKNOW	LEDGMENT OF RECEIPT:	
	M DEV 00 00/10/01	DATE:

IDT FRA-1509-01 REV. 00 09/18/01

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Refer To QCA-1795



### PRODUCT/PROCESS CHANGE NOTICE (PCN)

ATTACHMENT - PCN #: L0203-03

**PCN Type:** Fab Site Change

**Data Sheet Change:** None

**Detail of Change:** Transfer existing qualified products from Salinas, California Wafer Fab Facility (Fab 2) to

Hillsboro, Oregon Wafer Fab Facility (Fab 4).

		Current W	afer Fab			Transfer V	Vafer Fab	
Part Number	Manufacturing	Technology	Wafer	Die	Manufacturing	Technology	Wafer	Die
	Site		Size	Revision	Site		Size	Revision
IDT74ALVCF162835	Salinas, CA	CMOS 8	6 inch	A	Hillsboro, OR	CMOS 8	8 inch	A4
IDT74ALVCHS162830	Salinas, CA	CMOS 8	6 inch	AB	Hillsboro, OR	CMOS 8	8 inch	AB4
IDTCSP2510	Salinas, CA	CMOS 8	6 inch	Z	Hillsboro, OR	CMOS 8	8 inch	<b>Z</b> 4

Note: There is no change in die technology.

#### **Conversion schedule (Estimated)**

Base DeviceSample AvailabilityProduction ShipmentsIDT74ALVCF162835NowJune 15, 2002IDT74ALVCHS162830April 17, 2002June 15, 2002IDTCSP2510NowJune 15, 2002



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### ATTACHMENT - PCN #: L0203-03

Qualification Plan: QLG-02-07/QLG-02-08

		Test Results				
	Required Sample/ # Fails	74ALVCF162835	74ALVCHS162830 Expected 5/31/02	CSP2510 Expected 5/31/02		
Operating Life Test: Dynamic 1000 hrs @ 125°C or equivalent	116/0	116/0				
Bake & Ballshear Test @ 200°C / 4 ball bonds per device	5/0	5/0				
Temperature Cycling: (-65°C to +150°C, 500 cycles)	45/0	45/0				
HAST: (Biased, 100 Hrs. @ +130°C, +85%RH)	45/0	45/0				
ESD Human Body Model	3/0	3/0				
ESD Charged Device Model	3/0	3/0				
ESD Machine Model	3/0	3/0				
Latch up: (Tested to 1.5X Vcc)	10/0	10/0				

#### **Characterization Data:**

Characterization data is available upon request.